Invited Speech: Smart Fault Detection Using Artificial Intelligence

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About the Speaker
Tom Ho, with 30+ years of experience in the semiconductor industry, has held technical positions in Yield/Product/Test Engineering, Process and Product Development as well as executive positions in start-ups and publicly traded companies developing enterprise level analytic solutions for semiconductor, LCD, LED and other high-tech manufacturers.

He is currently President of BISTel America, based in Santa Clara, California, developing integrated factory automation solutions to improve manufacturing productivity for various industries.

Tom graduated from the University of California at Berkeley with a double-major in Chemical Engineering and Material Science.

Abstract

There has been many articles written on how Artificial Intelligence (AI) can help to increase performance, efficiency and productivity in manufacturing. One such opportunity is in the high-tech manufacturing industry, where AI can be leveraged to greatly improve the usability and accuracy of a Fault Detection & Classification (FDC) system.

This presentation will provide examples on how AI technologies can be used in FDC to improve detection coverage, detection precision and overall system productivity. In addition, insights will be shared on how AI can be further applied in the future to automate optimization through self-learning.